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| APPLICATION NO. | FILING DATE | FIRST NAMED INVENTOR | ATTORNEY DOCKET NO. | CONFIRMATION NO. | |
|-------------------|-------------------------------------|----------------------|---------------------|------------------|--|
| 10/522,569 | 11/17/2005 | Shuhei Ogawa | 033082M239 | 8765 | |
| 441 SMITH. GAM | 7590 08/14/2007. BRELL & RUSSELL | EXAMINER | | | |
| 1850 M STREI | ET, N.W., SUITE 800 | · | OLSEN, ALLAN W | | |
| WASHINGTO | N, DC 20036 | | ART UNIT | PAPER NUMBER | |
| | • | | 1763 | | |
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| | | , | MAIL DATE | DELIVERY MODE | |
| • | | | 08/14/2007 | PAPER | |

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

Advisory Action Before the Filing of an Appeal Brief

| Application No. | Applicant(s) | | |
|-----------------|--------------|---|--|
| 10/522,569 | OGAWA ET AL. | | |
| Examiner | Art Unit | | |
| Allan Olsen | 1763 | • | |

| · *** | Allan Olsen | | 1763 | | | | |
|--|---|--|--|---|--|--|--|
| The MAILING DATE of this communication appe | ars on the cover s | sheet with the c | orrespondence add | ress | | | |
| THE REPLY FILED <u>09 July 2007</u> FAILS TO PLACE THIS APPI | LICATION IN CON | DITION FOR AL | LOWANCE. | • | | | |
| 1. The reply was filed after a final rejection, but prior to or on this application, applicant must timely file one of the follow places the application in condition for allowance; (2) a No a Request for Continued Examination (RCE) in compliance time periods: | wing replies: (1) an itice of Appeal (with | amendment, aff appeal fee) in o | idavit, or other evider compliance with 37 C | nce, which FR 41.31; or (3) | | | |
| a) The period for reply expires 5 months from the mailing date | of the final rejection. | | | | | | |
| b) The period for reply expires on: (1) the mailing date of this A no event, however, will the statutory period for reply expire to | | | | | | | |
| Examiner Note: If box 1 is checked, check either box (a) or TWO MONTHS OF THE FINAL REJECTION. See MPEP 7 | 06.07(f). | | | | | | |
| Extensions of time may be obtained under 37 CFR 1.136(a). The date have been filed is the date for purposes of determining the period of exunder 37 CFR 1.17(a) is calculated from: (1) the expiration date of the set forth in (b) above, if checked. Any reply received by the Office later may reduce any earned patent term adjustment. See 37 CFR 1.704(b) NOTICE OF APPEAL | tension and the corre shortened statutory por than three months a | sponding amount eriod for reply origi | of the fee. The appropr inally set in the final Offi | iate extension fee ice action; or (2) as | | | |
| The Notice of Appeal was filed on A brief in comp filing the Notice of Appeal (37 CFR 41.37(a)), or any exte a Notice of Appeal has been filed, any reply must be filed | nsion thereof (37 C | FR 41.37(e)), to | avoid dismissal of th | | | | |
| AMENDMENTS | hut major to the date | a of filing a briaf | will not be entered b | | | | |
| The proposed amendment(s) filed after a final rejection, (a) They raise new issues that would require further co | | | | ecause | | | |
| (b) They raise the issue of new matter (see NOTE belo | | 3001011 (300 110 | 12 50.017), | | | | |
| (c) They are not deemed to place the application in being appeal; and/or | • | by materially re | ducing or simplifying | the issues for | | | |
| (d) They present additional claims without canceling a | corresponding num | nber of finally rej | ected claims. | | | | |
| NOTE: See Continuation Sheet. (See 37 CFR 1.1 | 16 and 41.33(a)). | | | | | | |
| 4. 🔲 The amendments are not in compliance with 37 CFR 1.1 | 21. See attached N | lotice of Non-Co | mpliant Amendment | (PTOL-324). | | | |
| 5. $\ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \$ | | | | ح. | | | |
| Newly proposed or amended claim(s) would be all non-allowable claim(s). | | | | _ | | | |
| 7. For purposes of appeal, the proposed amendment(s): a) how the new or amended claims would be rejected is protected. The status of the claim(s) is (or will be) as follows: | | | ll be entered and an e | explanation of | | | |
| Claim(s) allowed: Claim(s) objected to: Claim(s) rejected: | | | | | | | |
| Claim(s) withdrawn from consideration: | | | | | | | |
| AFFIDAVIT OR OTHER EVIDENCE B. The affidavit or other evidence filed after a final action, bu because applicant failed to provide a showing of good an was not earlier presented. See 37 CFR 1.116(e). | at before or on the o | date of filing a No s why the affidav | otice of Appeal will <u>no</u> vit or other evidence is | ot be entered s necessary and | | | |
| 9. The affidavit or other evidence filed after the date of filing entered because the affidavit or other evidence failed to c showing a good and sufficient reasons why it is necessar | overcome <u>all</u> rejecti | ons under appe | al and/or appellant fa | ils to provide a | | | |
| The affidavit or other evidence is entered. An explanation REQUEST FOR RECONSIDERATION/OTHER | = | • | | - | | | |
| 11. The request for reconsideration has been considered but | it does NOT place t | the application in | n condition for allowa | nce because: | | | |
| 12. ⊠ Note the attached Notice of References Cited (PTO-892 | · | | | | | | |
| 13 Other | | | | | | | |
| | 1 nr | 0. | • | | | | |
| • | -111 | 1 /m | Allan Olsen | | | | |

Primary Examiner Art Unit: 1763 Continuation of 3. NOTE: Applicant states:

"Claim 1 has been amended in part to include the contents of canceled claims 6 and 14 therein. Claim 7 has been amended in part to include the contents of canceled claims 13 and 15 therein.

Claims 1 and 7 have been further amended to more clearly present the steps of the claimed methods.

Applicants submit that the amendments herein do not raise new issues. Accordingly, Applicants respectfully request entry of this Amendment.

... Thus, both claims 1 and 7 now include the following features:

- (i) the etching method is carried out by a capacitively coupled plasma etching system, which forms a high-frequency electric field between a pair of opposed electrodes disposed in the processing vessel to generate the plasma; and
- (ii) the distance between the electrodes is such that a distance between a first of said electrodes and a wafer disposed on a second of said electrodes is from 30 to 90 mm."

The examiner notes that claim 14 is dependent upon claim 6, which in turn is dependent upon claim 1. Therefore, if the after-final amendment were to be entered, amended claim 1 would ostensibly be the equivalent of claim 14. However, claim 1, as presented in the after-final amendment is distinct from claim 14 because claim 14, by way of claim 6, requires that there be a pair of electrodes disposed in the processing vessel and this in not required by claim 1 as presented in the after-final amendment.

Furthermore, if the amendment were to be entered, further searching would be required because various combinations of limitations that were not previously presented in combination are now presented with each dependent claim. For example, the combination of limitations in claims 2 and 14 was not previously considered. Also, it is noted that claim

1 has been amended to include positive recitations of <u>"controlling"</u> a CD shift value and "causing" particular a residence time.

With respect to the rejection of claims as being unpatentable over Joubert IVO Desphande and FIVO Eriguchi, Applicant argues:

"Neither Joubert, Desphande nor Eriguchi teaches features (i) and (ii) above.

According to the Office Action, Joubert teaches the use of conventional etching sources, with specific mention of LAM TCP and Applied Material PDS reactors. The Examiner takes official notice that conventional etching sources, particularly the reactors named in Joubert, have an electrode spacing within the claimed 30-90 mm range. Joubert teaches the use of an induction coil coupled plasma etching system, wherein plasma is formed by using an induction coil. In such a system, the lower electrode of the system has nothing to do with the formation of the plasma. That is to say, the distance between the upper electrode (the first electrode) and the lower electrode (the second electrode) in the induction coil coupled plasma etching system is not selected based on whether a plasma will be formed."

The examiner notes that the induction coil of the LAM TCP and the Applied Materials PDS reactors is a source of capacitive coupling (see paragraph [0088] of Brcka, which is made of record with attached USPTO form 892). Furthermore, while the noted LAM TCP and Applied Materials PDS reactors are indeed ICP systems, Joubert is not limited to such reactors. In fact Joubert clearly teaches that "any conventional etching source" can be used. Joubert explicitly recites RIE (Reactive Ion Etching) as one such possible source and RIE etching apparatus commonly comprise the claimed pair of electrodes disposed with in the chamber with the claimed spacing. The gap between the electrodes is a known cause-effective variable and optimization of this parameter is well within the level of ordinary skill.